**Cryogenic probe station**

The Model CRX-VF is a versatile cryogen-free micro-manipulated probe station used for non-destructive testing of devices on full and partial wafers up to 51 mm (2 inches) in diameter. The CRX-VF is user configured with up to six ultra-stable micro-manipulated probe arms and is a platform for the measurement of electrical, electro-optical, parametric, high Z, DC, RF, and microwave properties of materials and test devices.

DC measurements can be optimized for low-noise, high-impedance (low leakage), or high-thermal contact to the device under test (DUT). RF measurements include configurations up to 67 GHz. Optical sources can be introduced through viewport windows or optional fiber-optic probe arm modification.

Using a single Sumitomo 4 K base temperature CCR, the CRX-VF is equipped with a vertical field superconducting magnet capable of a maximum of 22.5 KOe (2.25 T)\*. It provides efficient temperature operation and control over a temperature range of 10 K to 500 K without the operating expense of liquid cryogens. Each cryogenic stage is equipped with a sensor and heater to provide a fast thermal response and rapid warm-up for sample exchange.

